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Sheet 1 of 1 10-15-01

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1725	SERIAL NO. Filed Herewith		
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U.S. PATENT DOCUMENTS							
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							Yes No
	AM						
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
Dkt	AR		Hiratani, M. et al., "A Conformal Ruthenium Electrode for MIM Capacitors in Gbit DRAMs Using the CVD Technology Based on				
			Oxygen-Controlled Surface Reaction, IEEE, 2000 Symposium on VLSI Technology Digest of Technical Papers, pp. 102-103.				
Dkt	AS		Kim, Y. et al., "Growth of RuOx Thin Films by Metal Organic Chemical Vapor Deposition", IEEE 1999, pp. 501-502.				
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